



PATENT
Atty. Dkt. No. APPM/D03177.D1/CPVL/B/PJS
Serial No.: 10/848,403

AF/ITW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of:
Wang, et al.

Serial No.: 10/646,405

Confirmation No.: 9508

Filed: 8/22/2003

**For: Method and Apparatus For
Ionized Plasma Deposition**

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Group Art Unit: 1753

Examiner: Rodney Glenn McDonald

**MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

Dear Sir:

CERTIFICATE OF MAILING
37 CFR 1.8

SECOND RESPONSE TO FINAL OFFICE ACTION DATED JANUARY 10, 2006

In further response to the Final Office Action mailed January 10, 2006 and the Advisory Action dated March 28, 2006, having a shortened statutory period for response set to expire on April 10, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/003177.D1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 7 of this paper.